Velox™ 2.6 Highlights
Probe Station Control Software

The most powerful engineering software in the market
The new Velox 2.6 release concentrates on new hardware support for the CM300xi as well as usability enhancements for more user comfort. In particular, the Autonomous RF function has been improved in terms of accuracy and measurement speed. A free upgrade is available for existing customers.*

Support of the new compact MHU301 for CM300xi

- Material Handling Unit with SEMI-compliant load port for standard wafer cassettes
- Fully-automated test of up to 25 wafers in FOUP
- No manual handling of wafers required, reducing effort and risk of wafer breakage
- All wafers can be of different design
- Automatic pre-alignment of wafers
- Field-upgradeable to (already existing) CM300xi probe systems which have been prepared for a future MHU upgrade

Benefit:
SEMI-compliant automation in the smallest lab space

Extended capabilities of Autonomous RF Measurement Assistant

- 50 µm probe support
- Alignment wizards optimized
- Automation for Multi-line TRL calibration
- More threshold settings for exact measurement

Benefit:
Improved accuracy, higher application flexibility, ease of use
Enhanced AutoAlign

- Fully-automatic wafer X and Y alignment included (additionally to the theta alignment function)
- Reduced working steps
- Improved usability
- Most ergonomic and quickest way to align a wafer for 90% of use cases

Benefit:
Simplification of wafer setup

Unique wafer safety over power cycle

- Wafer tracking after power down or emergency stop

Benefit:
No more lost wafers in unexpected situations

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New automated light settings in SPECTRUM Vision System

- Microscope light settings adjust automatically depending on use case
- Enables switching between Aux sites and wafer without visibility limitation
- Reduces manual intervention during setting up

Benefit:
More automation for faster time to measurement

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Toolbar – additional status information

- Enhanced status information
- Higher safety in manual mode

Benefit:
More information for advanced users

* Requires Service visit.